

4934

Trend and Prospect of 3rd Gen. Semiconductor Materials Tainergy Tech Co., Ltd.

SiC

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Outline

- 1. Company Profile
- 2. Introduction & Application of 3rd Gen. Semiconductor Materials
- 3. Overview of SiC Market
- 4. SiC Substrate Process
- 5. Conclusions



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Company Profile

- Tainergy Tech Co., Ltd.
- IPO : Aug. 2011 (TSEC : 4934)
- Established : 2007/5/14
- Capital : NTD 2 Bill.
- President : Hsieh, Ching-Fu
- General Manager : Vincent Hsieh
- Operating Base : Zhongli/Taiwan

 Kunshan/China
 Hanoi/Vietnam
- Major Investor : Kenmec Shareholding % : 28.83%

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Major Product : Solar Cells /_____









Organizational Chart



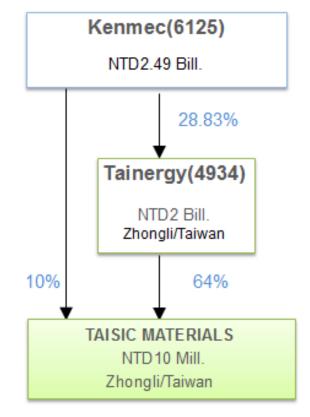


SiC BU



Subsidiary: TAISIC Materials Corp.

Founded : Jun. 2020 Representative : Kevin Hsieh Main Product : SiC Substrates Investors : Tainergy 64% Kenmec 10%





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Category of Semiconductor Materials SiC

| | Materials | Applications | Properties |
|----------------------|------------|----------------------------------|--|
| 1 st Gen. | Ge 🔨 Si | Microelectronics, IE | Abundant Si element in nature Mature purification & crystal growth technology Excellent isolation properties of SiO2 Restrictions on optoelectronic and HF applications due to Si physical nature |
| 2 nd Gen. | GaAs 	 InP | Communication, Illumination | GaAs \ InP material s rare on earth Poisonous , environmental unfriendly Suitable for HF, high speed, high power and optoelectronic devices |
| 3 rd Gen. | SiC 	 GaN | High Power 	 HF Communication | Known as Wide Band Gap semiconductors with electric properties between semiconductor and insulating materials. Sutiable for higher voltage, frequency and temperature applications |



Advantages of SiC Devices

High Power Applications

Ultra High Working Voltage

Ultra High Frequencies

More Stable at High Temp.

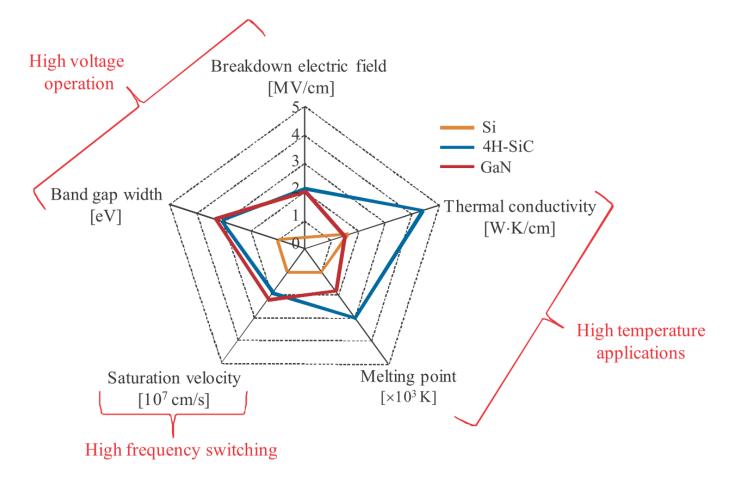
Excellent Radiation Resistance

Smaller Module Size



| Properties | | Si | SiC | GaN |
|---------------------------------|------------------------|------|------|------|
| Bandgap | eV | 1.12 | 3.26 | 3.39 |
| Electron Mobility | cm²/V-s | 1450 | 900 | 2000 |
| Electron Field for Breakdown | MV/cm | 0.3 | 3.5 | 3.5 |
| Saturated Drift Velocity | x 10 ⁶ cm/s | 10 | 22 | 25 |
| Thermal Conductivity | W/cm/K | 1.5 | 4.5 | 1.3 |

Comparison of Physical Characteristics SiC



Comparison of 2 SiC Substrates SiC

| | N-type | Semi-insulating |
|------------------------------|------------------|------------------|
| Resistivity Ohm-c m Range | 0.015-0.028 | > 1E6 |
| Orientation | 4° Off | On-axis |
| Thickness | 350μm +/-25μm | 500μm +/-25μm |
| Epitaxy | SiC | GaN |
| Applications | Electronic Power | RF |

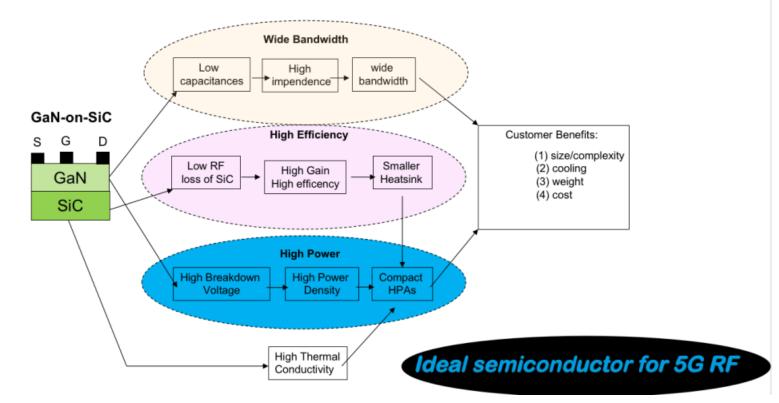
| | Sapphire | Si | SiC | GaN |
|--|----------|------|------|------|
| Lattice Constant (Å) | 2.75 | 5.43 | 3.08 | 3.19 |
| Lattice mismatch with GaN (%) | 16 | 17 | 3.4 | - |
| Coefficient of thermal expansion $(10^{-6}K^{-1})$ | 7.5 | 2.6 | 4.2 | 5.6 |
| Thermal conductivity (W/cm/K) | 0.2 | 1.5 | 4.5 | 1.3 |
| Maximum substrate commercially available | 8″ | 12" | 6″ | |

In addition to the electrical and optical characteristics, the main considerations are as follows:

- 1. The epitaxial materials have the same or similar crystal structure with the substrate, small lattice mismatch, good crystallization performance and low defect density;
- 2. Good interfacial properties are favorable for the nucleation and adhesion of epitaxial materials;
- 3. Good chemical stability and not easy to decompose and corrode in the temperature and atmosphere of epitaxial growth;
- 4. Good thermal properties, including good thermal conductivity and small thermal mismatch;
- 5. Good electrical characteristics to process for upper and lower structures;
- 6. Good mechanical properties, easy to process, including thinning, polishing and cutting;
- 7. Low price;
- 8. Large size.

GaN-on-SiC in PA Applications SiC

GaN on SiC Value on PA

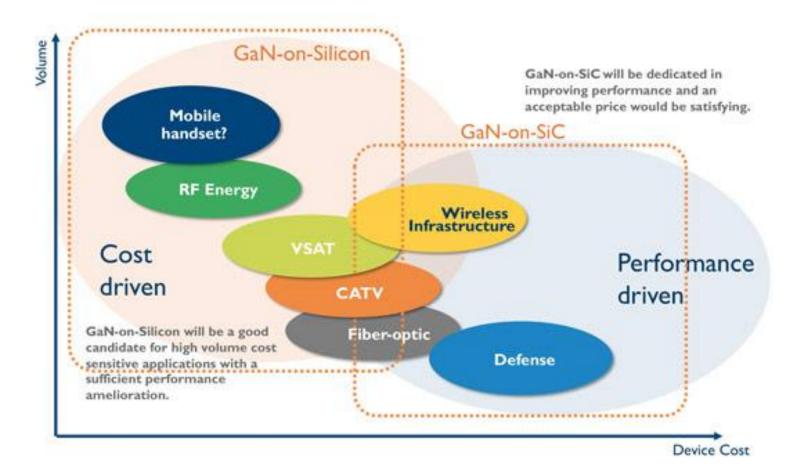


SiC Device Applications



| SiC Substrates | | | | |
|----------------|--|----------------------------|---------------------------------------|--|
| N-type | | | | SI |
| LED | Power Devices (SBD \ MOSFET) | | | MW Devices (HEMT) |
| <image/> | UPSImage: height blackImage: heig | <image/> <image/> <image/> | PV Wind Power Wind Power KRR | SG small cellsImage: SG small cellsImage: SG small cellsSatelliteImage: SatelliteImage: Satellite </td |

GaN-on-Sivs GaN-on-SiC



SiC

Applications of High Power SiC & Gab Modules

Low-Voltage Medium-Voltage High-Voltage Motor **PFC/Power supply PV** Inverter Smart Power Grid Ship&Vessels Control **Class D Audio** Rail Wind EV/HEV UPS Audio Amplifer Transport Mills 600V 900V 1.2kV 1.7kV <200V 3.3kV 6.5kV+ SiC diodes

Battle fields

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GaN-on-Si Transistors

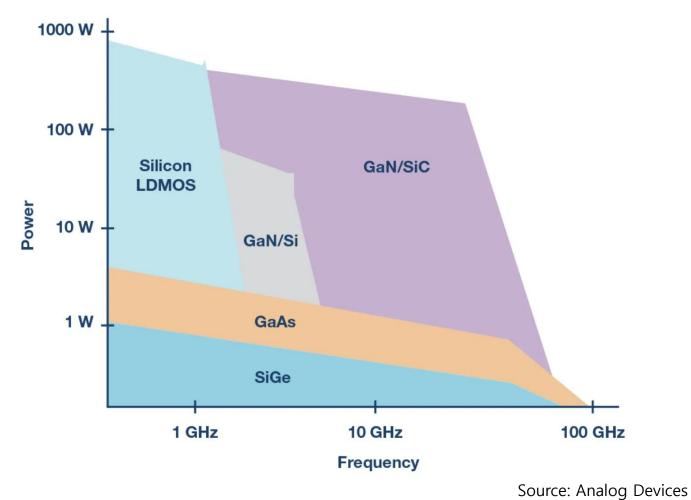
SiC Transistors



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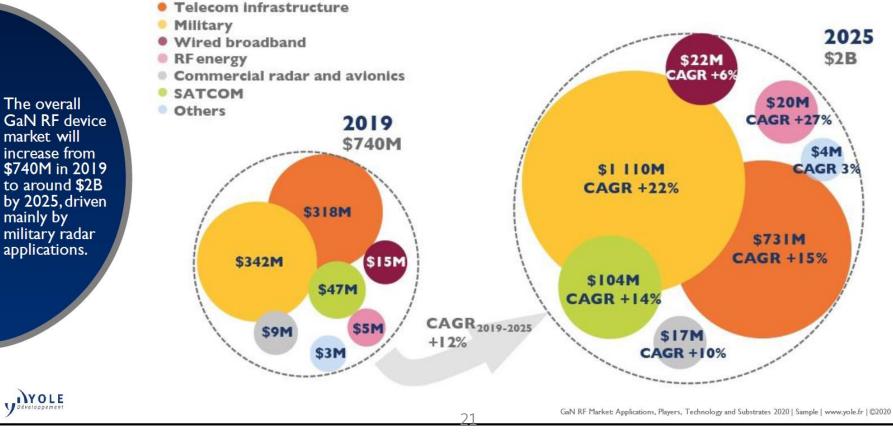
Power vs Frequency for Various Material SiC



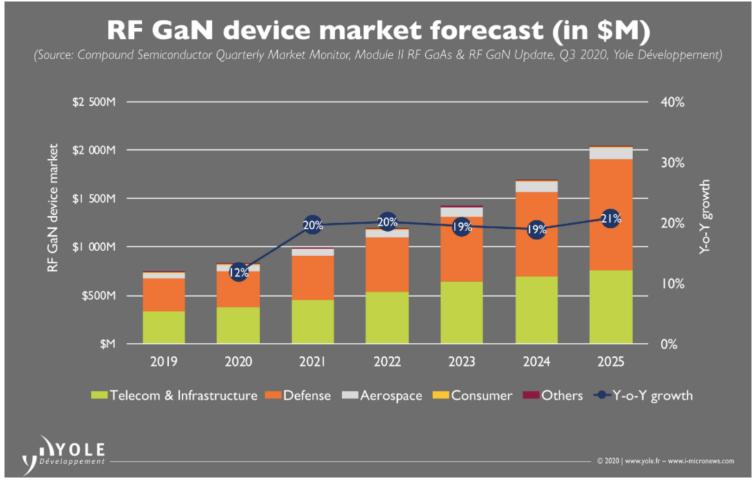
Prediction of RF GaN Device Market Sic

PACKAGED GAN RF DEVICE MARKET FORECAST

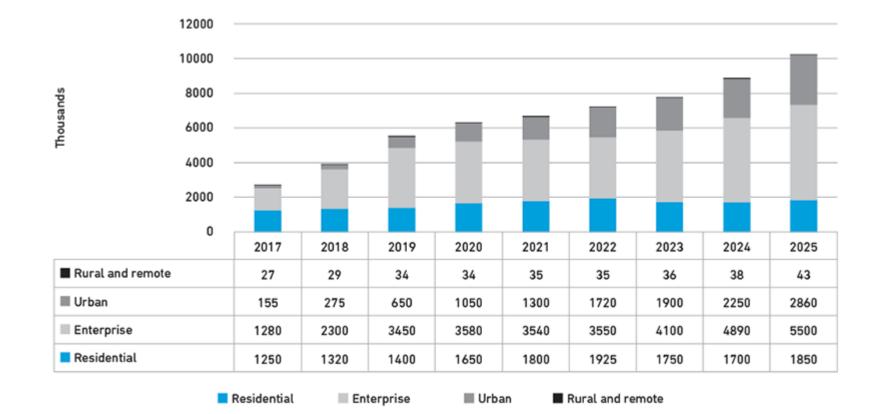
Split by application



Prediction of RF GaN Device Market Sic



Global Demands for 5G small cells

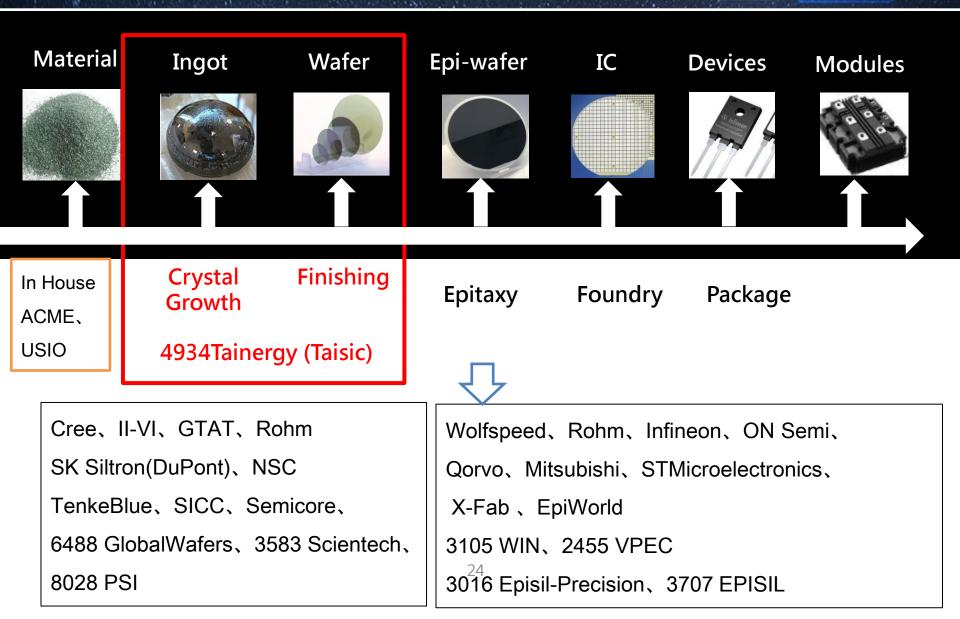


SiC

Global Demands for 5G small cells will be up to 10.25 millions

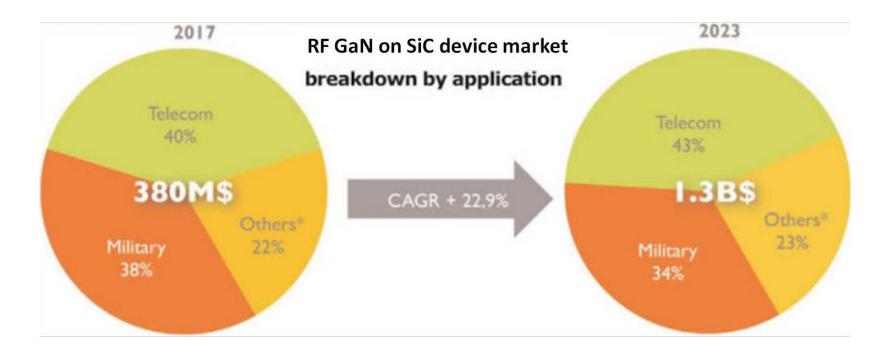
Industrial Chain of SiC





Prediction of SiC Communication Device market

It is estimated that the market growth will exceed 3 times in the next five years \rightarrow \$1.3 billion in 2023



SiC

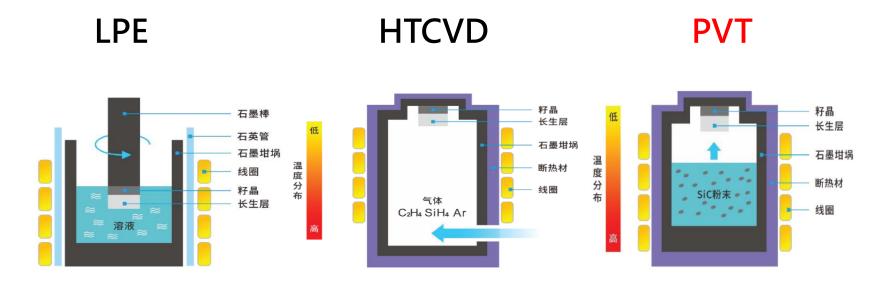


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Crystal Growth of SiC



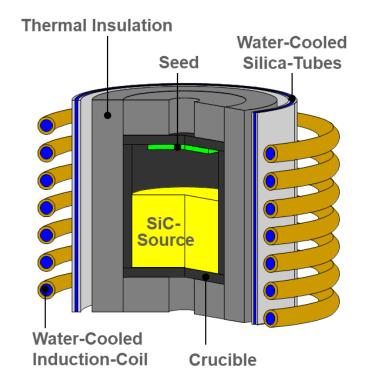


LPE: Liquid Phase Epitaxial

HTCVD: High Temperature Chemical Vapor Deposition PVT: Physical Vapor Transport

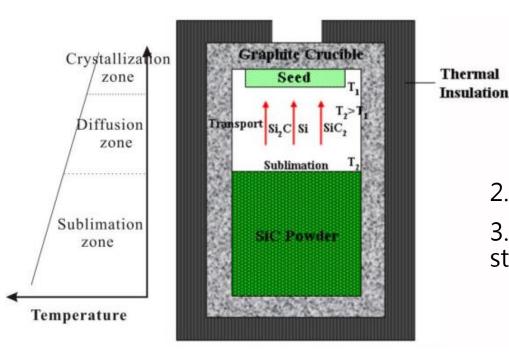
Schematic of SiC PVT Crystal GrowthSiC

- 1. it is impossible to in-situ observe the crystal growth in the black box of graphite crucible. The SiC crystal seeds, graphite crucible and high-purity SiC raw materials can not be used again. It has to destroy the crucible to confirm the success or failure of the SiC crystal growth.
- The crystal growth rate is slow –only
 20mm thick after 7 days' growth.
- 3. As SiC has more than 200 polytypes, needs accurate thermal field, flow field, electrical field control as well as accumulated experiences to grow large size, defect free and uniform 4H single crystal.



Growth Process of SiC Crystal by PVT Method





1. T > 1800°C · sublimationdecomposition reaction: SiC(s) = Si(g) + C(s)al $2SiC(s) = Si_2C(g) + C(s)$ $2SiC(s) = SiC_2(g) + Si(g)$

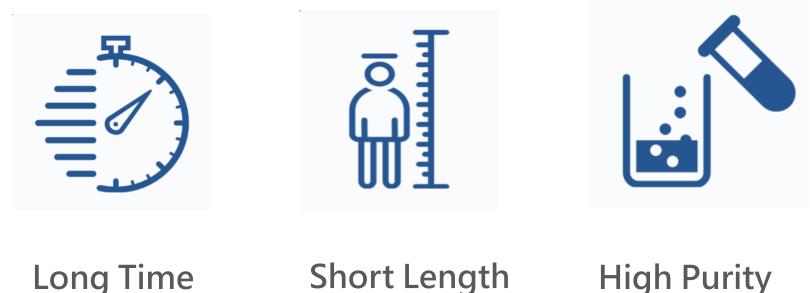
2. Gas phase transmission;

3. Recrystallization in supersaturated state:

 $SiC_2(g) + Si(g) = 2SiC(s)$

 $Si_2C(g) + SiC_2(g) = 3SiC(s)$

Features of SiC Crystal Growth sic



Si: 3~4 days SiC: 7 days

Short Length

Si: 200 cm SiC: 2 cm

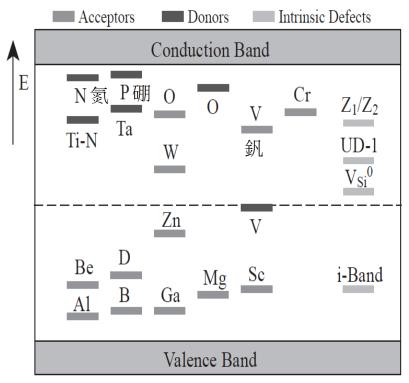
Raw materials and Seed

Summary of SI-SiC Crystal Growth SiC

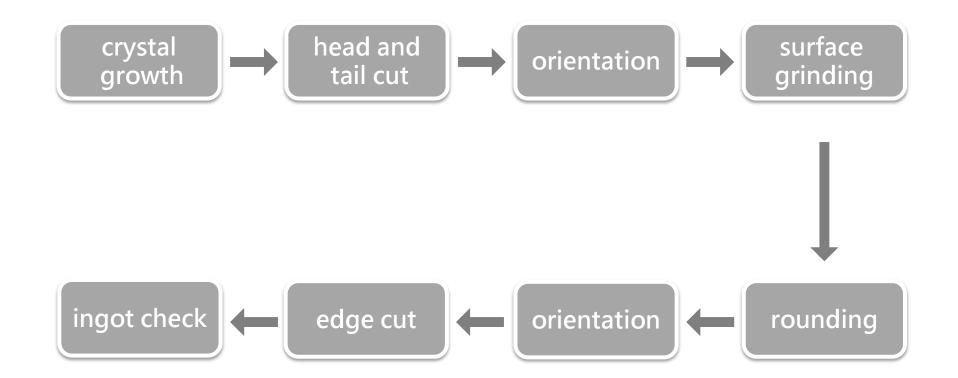
High purity Crystal Growth

- The resistance of SI-SiC substrate is required to be more than 1e6 Ω· cm. There are two technologies to meet requirements:
- By doping vanadium to modify the electrical properties of the substrate. It will cause crystal defects and results in reduced yield of components, which will increase the complexity of crystal manufacturing and increase the cost.
- By controlling the purity and defects in SiC crystal growth so as to increase the resistivity. In addition to high purity raw materials and low impurity in graphite crucibles, it is also necessary to overcome the nitrogen content in the environment. (the conductivity will be increased when the nitrogen content in SiC crystal is high).

Vanadium Doping

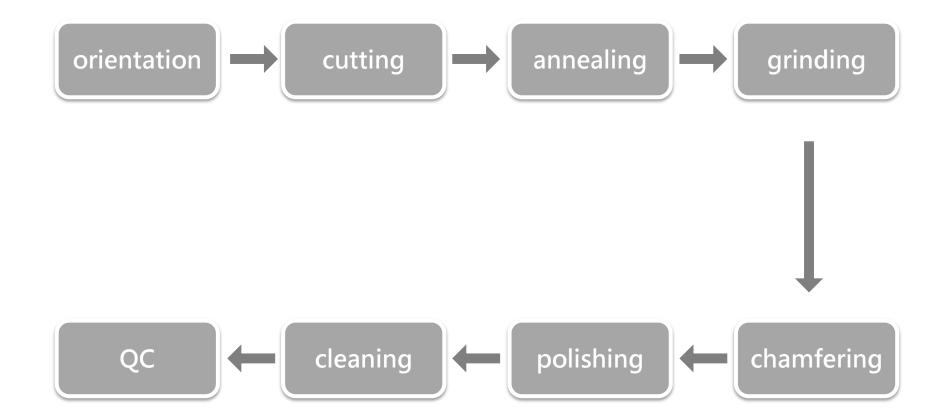


Process Flow of SiC Ingot



SiC

Process Flow of SiC Wafer



SiC



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Conclusions



- There will be explosively market growth in SiC applied in both power devices and HF communications in the near future.
- It is the prime time to invest in SiC substrate business, as the technology barriers and demand more than supply.
- Tainergy and the subsidiary TASIC have actively stepped into the field of SiC substrate manufacturing and developed our own core patents and technologies. We are now in the stage of product verification and certification, and mass production is expected to start in Q1, 2021.

Tainergy 4934 Into The New Semiconductor Era

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